

Electronic Patent Application Fee Transmittal

Application Number:	10593857			
Filing Date:	22-Sep-2006			
Title of Invention:	PLASMA CHAMBER HAVING PLASMA SOURCE COIL AND METHOD FOR ETCHING THE WAFER USING THE SAME			
First Named Inventor/Applicant Name:	Nam Hun Kim			
Filer:	Peter C. Hsueh/Shelley Johnson			
Attorney Docket Number:	58409/N305			
Filed as Large Entity				
U.S. National Stage under 35 USC 371 Filing Fees				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:				
Pages:				
Claims:				
Miscellaneous-Filing:				
Petition:				
Patent-Appeals-and-Interference:				
Post-Allowance-and-Post-Issuance:				
Certificate of correction	1811	1	100	100
Extension-of-Time:				

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
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Total in USD (\$)				100